

00862.003013.1

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	:	
)	Prior Examiner: K. Brown
Hisaaki OGURI et al.	:	
)	Prior Group Art Unit: 2851
Application No.: Continuation of Appln.:	:	
No. 09/388,372, filed)	
September 1, 1999	:	
)	
Filed: January 31, 2002	:	
)	
For: POSITION DETECTION	:	January 31, 2002
APPARATUS HAVING A)	
PLURALITY OF DETECTION	:	
SECTIONS, AND EXPOSURE)	
APPARATUS	:	

The Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

To comply with the duty of disclosure under 37 CFR 1.56 and in accordance with the practice under 37 CFR 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 Form. Copies of the listed documents are also enclosed.

(1) Japanese patent document No. 7-302748 relates to a semiconductor manufacturing apparatus having a plurality of measurement devices and a semiconductor manufacturing method using the same. This document corresponds to U.S. Patent No. 5,658,700, a copy of which is also enclosed.

(2) Japanese patent document No. 10-289871 relates to a projection exposure device.

(3) Japanese patent document No. 10-284393 relates to an aligner and fabrication of a device.

(4) Japanese patent document No. 10-64980 relates to a device and a method for detecting surface position.

(5) Japanese patent document No. 9-246356 relates to a surface position setting method.

(6) Japanese patent document No. 9-236425 relates to a surface position detector.

(7) Japanese patent document No. 9-45608 relates to a surface position detection method.

(8) Japanese patent document No. 7-201698 relates to a pattern exposing sensitive layer forming method and a semiconductor circuit using it.

(9) Japanese patent document No. 3-253917 relates to a method and device for setting an interval of first and second objects.

(10) Japanese patent document No. 57-204547 relates to an exposing method.

(11) Japanese patent document No. 11-176735 relates to a surface position detection method and aligner using the same.

(12) Japanese patent document No. 11-121320 relates to a method and device for detecting surface position.

(13) Japanese patent document No. 11-111610 relates to an aligning method and equipment thereof.


(14) Japanese patent document No. 11-191522 relates to a method and apparatus for exposure.

Applicants request that the Examiner consider the cited information and return an initialed copy of the enclosed PTO-1449 Form indicating that such information has been considered.

Applicants believe that no fees should be incurred in connection with filing this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fees be associated herewith. A duplicate of this paper is enclosed for this purpose.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,


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SEW/eab

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) January 31, 2002		ATTY DOCKET NO. 00862.003013.1	APPLICATION NO. Continuation of Appln. No. 09/388,372
APPLICANT Hisaaki OGURI et al.		FILING DATE January 31, 2002	
GROUP 2851			

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	5,658,700	08/19/1997	Sakai	430	30		
	5,593,800	01/14/1997	Fujloka et al.	430	5		
	5,661,408	08/26/1997	Kamieniecki et al.	324	765		
	5,917,580	06/29/1999	Ebinuma et al.	355	53		
	5,760,879	06/02/1998	Shinonaga et al.	355	55		

FOREIGN PATENT DOCUMENTS							
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT		
10-289871	10/27/1998	Japan			Abstract		
10-284393	10/23/1998	Japan			Abstract		
10-064980	03/06/1998	Japan			Abstract		
9-246356	09/19/1997	Japan			Abstract		
9-236425	09/09/1997	Japan			Abstract		
9-045608	02/14/1997	Japan			Abstract		
7-302748	11/14/1995	Japan			No		
7-201698	08/04/1995	Japan			Abstract		
3-253917	11/13/1991	Japan			Abstract		
57-204547	12/15/1982	Japan			Abstract		

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)	

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

